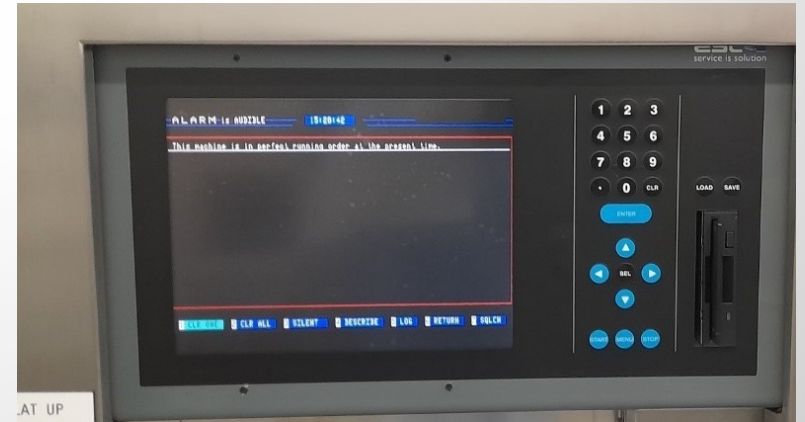




S O S G R O U P

LAM Research
4520i Oxide Etch 150mm Configuration
SN 2471

LAM Research 4520i Oxide Etch SN 3660



LAM Research

4520i Oxide Etch SN 2471



Tool Model : 4520i
Tool Serial Number : 2471
Bulkhead system mount w/tunnel covers
Hine 38A open cassette Send/Receive indexers
Software Version: Classic 7,31-42
Oxide etcher, 6"
Clamp type, ESC
RF power Rack AE PDW2200 RFG1250 13,56MHz
AE Isotropic Module
Chiller Unit (none/To customer Spec)
AC Rack AC Power Distribution
Moving gap
Back Helium Colling
Main Power 208V, 3 Phase, 5Wire, 175A, 60/
Belt driven load station
Standard load station shuttle spatula
Upper chamber gap drive encoder
Dip PCB for RF power tuning
Aluminum upper chamber electrode

Single lower chamber endpoint detector (405/520nm) Non-
-heated endpoint window
Low pressure chamber manifold
HPS valve for chamber isolation
AC--2 chamber pressure control
Lower chamber RGA port
8 -- Gas box Orbital gas box
Gas 1: AR 375sccm
Gas 2: CF4 100 sccm
Gas 3: CHF3 50 sccm
Gas 4: He 200 sccm
Gas 5: O2 20 sccm
Gas 6: N2 200 sccm
Gas 7 NF3 500 sccm
Gas 8: He 1000sccm
UPC: He (50 sccm)
AC input box for AC power inlet
Trip breakers AC/DC power box

Solutions on Silicon BV

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- **Equipment Support**
PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts
- **Process Support**
Process design, Improvement, Fab-to-Fab Transfer and Integration
- **Refurbishment**
From custom to complete refurbishment
- **Relocation**
Auditing, Fingerprinting, Decommissioning, Installation, Acceptance
- **Materials**
Supplier of first class second source materials

